What is claimed is:

- 1 1. A self-aligned fabrication process for a nozzle
- 2 plate of an inkjet print head, comprising the steps of:
- 3 providing a substrate having at least one activated
- 4 device thereon;
- 5 forming a first film on the substrate;
- 6 forming a second film on the first film;
- 7 defining the second film to form a convex portion
- 8 corresponding to the activated device, exposing a
- 9 part of the surface of the first film;
- 10 forming a third film on the exposed surface of the
- 11 first film, covering the convex portion;
- removing the third film on the convex portion; and
- etching the convex portion and the first film under the
- 14 convex portion to form a via.
- 1 2. The self-aligned fabrication process for a nozzle
- 2 plate of an inkjet print head as claimed in claim 1, wherein
- 3 the substrate is a silicon substrate.
- 3. The self-aligned fabrication process for a nozzle
- 2 plate of an inkjet print head as claimed in claim 1, wherein
- 3 the third film is made of spin-on-glass.
- The self-aligned fabrication process for a nozzle
- 2 plate of an inkjet print head as claimed in claim 1, wherein
- 3 the third film on the convex portion is removed by etching
- 4 to expose the surface of the convex portion.

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- 5. The self-aligned fabrication process for a nozzle
- 2 plate of an inkjet print head as claimed in claim 1, wherein
- 3 the third film on the convex portion is removed by
- 4 photolithography.
- 1 6. The self-aligned fabrication process for a nozzle
- 2 plate of an inkjet print head as claimed in claim 1, wherein
- 3 the via is formed by plasma dry etching.
- 1 7. The self-aligned fabrication process for a nozzle
- 2 plate of an inkjet print head as claimed in claim 6, wherein
- 3 the plasma dry etching uses oxygen as the main etching gas.
- 1 8. The self-aligned fabrication process for a nozzle
- 2 plate of an inkjet print head as claimed in claim 1, wherein
- 3 the first film is a polymer film.
- 9. The self-aligned fabrication process for a nozzle
- 2 plate of an inkjet print head as claimed in claim 1, wherein
- 3 the second film is a polymer film.
- 1 10. The self-aligned fabrication process for a nozzle
- 2 plate of an inkjet print head as claimed in claim 1, wherein
- 3 the activated device is a thin-film heater.
- 1 11. A self-aligned fabrication process for a nozzle
- 2 plate of an inkjet print head, comprising the steps of:
- 3 providing a silicon substrate having at least one
- 4 activated device thereon;
- 5 forming a first film on the substrate;
- 6 forming a second film on the first film;

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- 7 defining the second film to form a convex portion
- 8 corresponding to the activated device, exposing a
- 9 part of the surface of the first film;
- 10 forming a spin-on-glass film on the exposed surface of
- 11 the first film, covering the convex portion;
- removing the spin-on-glass film on the convex portion;
- 13 and
- 14 etching the convex portion and the first film under the
- 15 convex portion to form a via.
 - 1 12. The self-aligned fabrication process for a nozzle
 - 2 plate of an inkjet print head as claimed in claim 11,
 - 3 wherein the spin-on-glass film on the convex portion is
 - 4 removed by etching to expose the surface of the convex
 - 5 portion.
 - 1 13. The self-aligned fabrication process for a nozzle
 - 2 plate of an inkjet print head as claimed in claim 11,
 - 3 wherein the spin-on-glass film on the convex portion is
 - 4 removed by photolithography.
 - 1 14. The self-aligned fabrication process for a nozzle
 - 2 plate of an inkjet print head as claimed in claim 11,
- 3 wherein the via is formed by plasma dry etching.
- 1 15. The self-aligned fabrication process for a nozzle
- 2 plate of an inkjet print head as claimed in claim 14,
- 3 wherein the plasma dry etching uses oxygen as the main
- 4 etching gas.

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- 1 16. The self-aligned fabrication process for a nozzle
- 2 plate of an inkjet print head as claimed in claim 11,
- 3 wherein the first film is a polymer film.
- 1 17. The self-aligned fabrication process for a nozzle
- 2 plate of an inkjet print head as claimed in claim 11,
- 3 wherein the second film is a polymer film.
- 1 18. The self-aligned fabrication process for a nozzle
- 2 plate of an inkjet print head as claimed in claim 11,
- 3 wherein the activated device is a thin-film heater.